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# **Microfabricated and Nanofabricated Systems for MEMS/NEMS 8**

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Published by  
**The Electrochemical Society**

65 South Main Street, Building D  
Pennington, NJ 08534-2839, USA  
tel 609 737 1902  
fax 609 737 2743  
[www.electrochem.org](http://www.electrochem.org)

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**Vol. 16 No. 14**

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Published by:

The Electrochemical Society  
65 South Main Street  
Pennington, New Jersey 08534-2839, USA

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e-mail: [ecs@electrochem.org](mailto:ecs@electrochem.org)  
Web: [www.electrochem.org](http://www.electrochem.org)

ISSN 1938-6737 (online)  
ISSN 1938-5862 (print)

ISBN 978-1-56677-660-8 (PDF)  
ISBN 978-1-60768-013-0 (Softcover)

Printed in the United States of America.

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## **Table of Contents**

<i>Preface</i>	<i>iii</i>
<b>Chapter 1</b>	
<b>Sensors and Biosensors</b>	
Layer-by-Layer Nano Self-Assembly of pH Sensors Based on Polyelectrolytes and Carboxylated Carbon Nanotubes	3
<i>D. Lee and T. Cui</i>	
Control of Cellular Adhesion within Microfluidic Device using Electrochemical Biolithography and Dielectrophoresis for Cell-Based Assay	11
<i>M. Hashimoto, H. Kaji and M. Nishizawa</i>	
<b>Chapter 2</b>	
<b>Fabrication Processes</b>	
The Role of Organic Additives in the Localized Copper Plating: Flat, Dish, and Domed Shape Copper Bumps	23
<i>L. Castoldi, A. Lodi and G. Visalli</i>	
Cleaning of Gold Interconnection Surface by Low-temperature Hydrogen Annealing for MEMS Device Fabrication	29
<i>T. Sakata, K. Kuwabara, K. Ono, N. Sato, K. Machida and H. Ishii</i>	
HF Vapor Release Assessment to Address NEMS Applications	37
<i>L. Lachal, S. Auclair, P. Lavios, J. Finet, R. Assidi, M. Klein, M. Vaudaine, F. Delaguillaumie, C. Marcoux, P. Andreucci, H. Grange, A. Berthelot, R. Garcia-Santana, F. Lasbordes, E. Lajoinie, O. Louveau and J. Chiaroni</i>	
Silicon Dry Etching Process for High Topography Sub-micro and Nano-devices	45
<i>A. De Luca, F. Ritton, M. Gelly, J. Buckley and M. Heitzman</i>	
Mechanical Properties of Polycrystalline Silicon formed by Al-2%Si Induced Crystallization	51
<i>J. Lai and T. King Liu</i>	

## Chapter 3 Sensors and Fluidic Devices

Large-Scale Polycrystalline SiC Micromachining Technologies <i>C. Roper, R. Howe and R. Maboudian</i>	63
The Development of Metal Oxide Chemical Sensing Nanostructures <i>G. Hunter, R. Vander Wal, J. Xu, L. Evans, G. Berger and M. Kullis</i>	73
Nanowires Synthesis and Characterization for Their Chemical Sensor Application <i>J. Deepak, Y. Lu and J. Li</i>	85

## Chapter 4 Poster Session

Fabrication of X-ray Grating Using X-ray Lithography Technique <i>D. Noda, H. Tsujii, N. Takahashi and T. Hattori</i>	97
Enhancement of Thermal Properties of Polymer-Coated Noble Metal Nanoparticles Using Plasmid DNA <i>T. Endo, Y. Yanagida and T. Hatsuzawa</i>	103
Evaluation of Alkyl-chain-length Dependency for Localized Surface Plasmon Resonance Optical Characteristics <i>Y. Kawakami, T. Endo, Y. Yanagida, T. Hatsuzawa and E. Tamiya</i>	107
Cell Cultivation on the Porous Silicon Surface for Cell Chip Application <i>Y. Yanagida, S. Naito, Y. Tanaka, T. Endo and T. Hatsuzawa</i>	113
Comparison of a Microfluidic Gas-Intake Devices with Pillar-Type and Microfluidic Membrane-Type Structures <i>M. Amano, T. Arakawa, H. Sato, T. Sekiguchi, S. Shoji, H. Kudo, H. Saito and K. Mitsubayashi</i>	117
Author Index	123